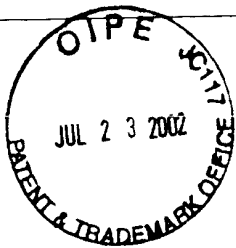
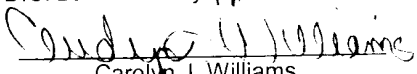


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Atty. Docket No. (Opt.) FOS1100-1754
	RECEIVED JUL 19 2002 PC 1700
	Applicant Robert Jackson
	Application Number 10/038,745
	Filed January 2, 2002
For METHOD AND SYSTEM FOR ON-SITE GENERATION AND DISTRIBUTION OF A PROCESS GAS	
Group Art Unit 1754	Examiner Unknown

Commissioner for Patents
Washington, D.C. 20231

<p align="center">Certification Under 37 C.F.R. §1.8</p> <p>I hereby certify that the documents listed below are being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on July 19, 2002.</p> <p align="center"> Carolyn J. Williams</p>
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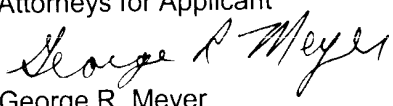
Applicant respectfully requests, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the art listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. A copy of the art is enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to patentability of the present application.

While Applicant believes no fees are due, if any fees are due, the Commissioner is hereby authorized to charge Deposit Account No. 50-0456 of Gray Cary Ware & Freidenrich LLP.

Applicant respectfully submits that the claims of Applicant's above-referenced patent application are patentably distinguishable from these references.

Respectfully submitted,

Gray Cary Ware & Freidenrich LLP
Attorneys for Applicant


George R. Meyer
Reg. No. 35,284

Date: July 18, 2002
1221 S. MoPac Expressway, Suite 400
Austin, Texas 78746
Tel. (512) 457-7093
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FORM PTO 1449 US Department of Commerce
Patent and Trademark Office

ATTY DOCKET NO.:
FOC1100-1

SERIAL NO.:
10/038,745

APPLICANT(S):
Robert Jackson

FILING DATE:
January 2, 2002

GROUP ART UNIT:
1754

PATENT NO. OF PARENT:
n/a

ISSUE DATE OF PARENT:
n/a

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**



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TC 1700

U.S. PATENT DOCUMENTS

EXAM. INITIALS		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
	A1	3,976,447	8/24/76	Merchant, et al.	55	71	3/11/75
	A2	4,960,488	10/2/90	Law, et al.	156	643	12/19/89
	A3	5,207,836	5/4/93	Mei Chang	134	1	6/3/92
	A4	5,336,832	8/9/94	Alfred E. Keller	585	710	11/6/92
	A5	5,549,802	8/27/96	Xin S. Guo	204	298.11	10/24/94
	A6	5,565,038	10/15/96	Ethan Ashley	134	2	5/16/91
	A7	5,685,916	11/11/97	Ye, et al.	134	1.1	7/7/95
	A8	5,756,400	5/26/98	Ye, et al.	438	710	12/8/95
	A9	5,788,778	8/4/98	Shang, et al.	134	1	9/16/96
	A10	5,788,799	8/4/98	Steger, et al.	156	345	6/11/96
	A11	5,844,195	12/1/98	Fairbairn, et al.	219	121.43	11/18/96
	A12	6,020,035	2/1/00	Gupta, et al.	427	534	10/29/96
	A13	6,029,718	2/29/00	Jackson, et al.	141	231	6/26/98
	A14	6,109,206	8/29/00	Maydan, et al.	118	723IR	5/29/97
	A15	6,159,333	12/12/00	Gupta, et al.	156	345	10/8/98
	A16	6,255,222	7/3/01	Xia, et al.	438	710	8/24/99
	A17	6,264,852	7/24/01	Herchen, et al.	216	60	6/16/00
	A18	6,271,148	8/7/01	Kao, et al.	438	727	10/13/99
	A19	6,352,081	3/5/02	Lu, et al.	134	22.1	7/9/99

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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ATTY DOCKET NO.:
FOC1100-1

SERIAL NO.:
10/038,745

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

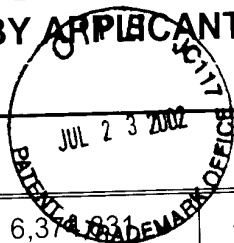
APPLICANT(S):
Robert Jackson

FILING DATE:
January 2, 2002

GROUP ART UNIT:
1754

PATENT NO. OF PARENT:
n/a

ISSUE DATE OF PARENT:
n/a



A20	6,374,831	4/23/02	Chandran, et al.	134	1.1	2/4/99
A21	6,379,575	4/30/02	Yin, et al.	216	67	10/21/97
A22	6,387,288	5/14/02	Bjorkman, et al.	216	67	4/21/00
A23	2002/0074013A1 09/741,529	published 6/20/02	Shang, et al.	134	1.1	12/19/00

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION (YES/NO)
B1	EP0697467A1	21.02.1996	Europe	C23C	16/44	Yes
B2	WO 99/06611	11.02.1999	WO	C23C	16/44	Yes
B3	WO 99/28538	10.06.1999	WO	C25B	9/00	Yes
B4	EP0965661A2	22.12.1999	Europe	C25B	9/00	Yes
B5	EP1076355A2	14.02.2001	Europe	H01L	21/00	Yes

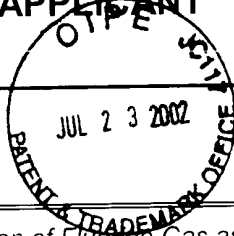
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages)

C1	<i>Kinetics of Gaseous Fluorine Reactions</i> , by Rudy Toon and Myron Kaufman. Progress in Reaction Kinetics, 1975, Vol. 8, No. 2, pp. 81-93
C2	VLSI Technology, Sze, Section 8.3 – Dry Etching, McGraw-Hill Book Co., pp. 312-317 (1983)
C3	MKS ASTeX® Products Announces ASTRON®e Ser High Flow Reactive Gas Generators for Process Chamber Cleaning Applications, Information printed from website www.astex.com/prastrone.html (2001)

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO 1449 US Department of Commerce Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY DOCKET NO.: FOC1100-1	SERIAL NO.: 10/038,743
	APPLICANT(S): Robert Jackson	
	FILING DATE: January 2, 2002	GROUP ART. UNIT: 1744
	PATENT NO. OF PARENT: n/a	ISSUE DATE OF PARENT: n/a



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C4	<i>Evaulation of Fluorine Gas as an Alternative Plasma-Enhanced Chemical Vapor Deposition Chamber Clean Chemistry; by Y. Ohira, et al., Semiconductor CVD Chamber Cleaning Project, Research Institute of Innovative Technology for the Earth (RITE), Japan.</i>
C5	<i>Evaluation of Fluorine Gas as an Alternative PE-CVD Chamber Cleaning Chemical, by Yutaka Ohira, et al., June, 2002.</i>

TECHNICAL STAFF
AUG 10 2002

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.